

# Photo-oxidized high-K Dielectric for van der Waals Nano-electronics and Opto-electronics

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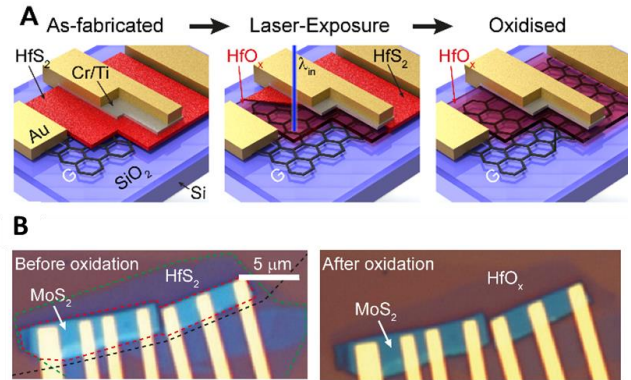
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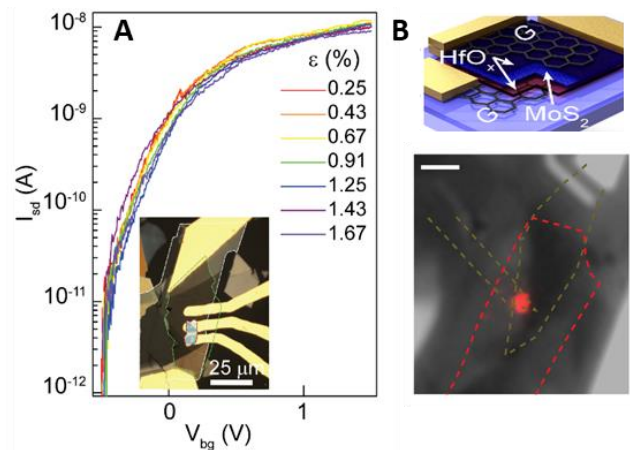
Abstract

Integration of van der Waals heterostructure with high-K oxides is needed to improve the device performance. However, it is limited by the traditional techniques of high-k deposition, which trend to damage the 2D crystals. Here we demonstrate an approach to incorporate a high-K oxide dielectric within van der Waals heterostructure devices without damaging the 2D crystals. This can be achieved by transforming few layer HfS<sub>2</sub> crystals embedded within heterostructures into HfO<sub>x</sub> by in-situ laser oxidation. The resultant oxide has a dielectric constant of  $K \sim 15$  and the thickness is determined only by the layer number of the parent HfS<sub>2</sub> crystal. We demonstrate the use of this oxide into a broad range of fundamental nano-electronic and optoelectronic devices such as flexible field effect transistors based on transition metal dichalcogenide (TMDC) channels, dual gated graphene transistors, resistive switching random access memories as well as light emitting and detecting tunnelling transistors using thin HfO<sub>x</sub> barrier. The approach of embedding a high k-oxide could be important for future flexible van der Waals electronics

Figures



**Figure 1: Heterostructure processing route.** (A) The transformation of HfS<sub>2</sub> layers embedded within heterostructure into HfO<sub>x</sub> using laser oxidation. (B) Optical image of Graphene/HfS<sub>2</sub>/MoS<sub>2</sub> heterostructure device before and after photo-oxidation



**Figure 2: Examples of the use of ultra-thin photo-oxidized HfO<sub>x</sub> dielectric in different types of devices** (A) TMDC flexible field-effect transistor. (B) Vertical light emitting device.